Docket Number (Optional) TWI-10820 Application Number 09/629,407 Applicant(s) Applicant(s) Allan Rosencwaig et al. Filing Date August 1, 2000 Croup Art Unit August 1, 2000 Application Number 09/629,407 Application Number 09/629,407

U.S. PATENT DOCUMENTS

M. H.C.	Ref	DOCUMENT NUMBER	DATE	Name	CLASS	SUBCLASS	FILING DATE
	BA				<u> </u>		
	BB					<u> </u>	

FOREIGN PATENT DOCUMENTS

		DOCUMENT					TRANSLATION	
	REF	Number	DATE	COUNTRY	CLASS	SUBCLASS	YES	No
HRS	BC	2720131	11/21/1997	Japan (w/translation)	G01N	23/207	X	
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OTHER DOCUMENTS

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HRS	BE	K. Sakurai et al., "Fourier Analysis of Interference Structure in X-Ray Specular Reflection from Thin Films," <i>Jpn. J. Appl. Phys.</i> , Vol. 31, 1992, pp. L113-L115.
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Examiner $\mathcal{H}(\mathcal{C})$	Date Considered 2-19-02
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not in conformance and not considered. Include Copy of this	s form with next communication to applicant.



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Sheet 1 of 1

FORM PTO-14- (Rev. 7-80)	Atty Docket No. Appln. No. 09/629,407									
	1	NFORMATION DISCL	Applicant(s) Allan Rosencwaig et al.							
(Use severa	l sheet	s if necessary)				Group 2876				
			U.	.s. patent docume	NTS					
*Examiner Initials		Document Number	Date	Name		Class	Subclass		Filing Date	
HK5	AA	5,371,582	12/06/1994	Toba et al.		356	73		07/30/1993	
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HKS	AE	0 352 740	07/25/1989	EPC		HO1L	21/306			
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				OTHER DOCUMENTS	-		-2			
	AH									
	AI						_			
Examiner HK5					Date Considered 2-17-02					
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